



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Scott G. Meikle

Application No.

09/649.427

Confirmation No.: 7170

Filed

For

August 28, 2000 METHOD AND APPARATUS FOR FORMING A

PLANARIZING PAD HAVING A FILM AND TEXTURE

ELEMENTS FOR PLANARIZATION OF MICROELECTRONIC

SUBSTRATES

Examiner

Charlotte A. Brown

Art Unit

1765

108298511US Docket No.

(Client Ref. No.: 00-0176)

October 3, 2002 Date

Assistant Commissioner for Patents Washington, DC 20231

RESPONSE UNDER 37 C.F.R. § 1.111

Dear Commissioner:

This paper responds to the Office Action in this patent application mailed July 3, 2002. Please reconsider the application in light of the following remarks.

In The Claims:

Please cancel claims 24-54

A method for forming a planarizing medium for planarizing a microelectronic substrate, comprising:

separating a planarizing medium material into discrete elements;

[10829-8511/SL022740.266]

10/3/02